

**INFORMATION DISCLOSURE
STATEMENT BY APPLICANT**

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Page 1 of 1

Application Number	10/734684
Filing Date	December 12, 2003
First Named Inventor	Theiss, Steven D
Art Unit	1765
Examiner Name	
Attorney Case Number	58355US002

U.S. Patent Documents

Exam. Init.*	Cite No.	Document Number	Publication Date or Issue Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Doc. Number-(Kind Code if Known)			
80	A1	US- 5,536,319	07/16/96	Wary et al.	
	A2	US- 5,846,694	12/08/98	Strand et al.	
	A3	US- 6,087,270	07/11/00	Reinberg et al.	
	A4	US- 6,319,784 B1	11/20/01	Yu et al.	
	A5	US- 6,433,359	08/13/02	Kelley et al.	
	A6	US- 6,617,609	09/09/03	Kelley et al.	
	A7	US- 2002-0167067 A1	11/14/02	Kim	
	A8	US- 2003-0102471 A1	06/05/03	Kelley et al.	
	A9	US- 2003-0105365 A1	06/05/03	Smith et al.	
	A10	US- 2003-0100779 A1	05/29/03	Vogel et al.	
	A11	US- 2003-0150384 A1	08/14/03	Baude et al.	
	A12	US- 2003-0151118 A1	08/14/03	Baude et al.	
1/2	A13	US- 2003-0152691 A1	08/14/03	Baude et al.	

OTHER DOCUMENTS

Exam. Init.*	Cite No.	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published	Translation (Check if yes)
80	C1	S.M. Sze, Physics of Semiconductor Devices, 2 nd Ed., John Wiley and Sons, p. 492, New York (1981)	
	C2	NIST Special Publication 922 "Polycyclic Aromatic Hydrocarbon Structure Index," U.S. Govt. Printing Office, by Sander & Wise (1997)	
	C3	P. Reinig et al., "Crystalline Silicon Films Grown by Pulsed DC Magnetron Sputtering", J. Non-Crystalline Solids, 299-302, pp. 128-132 (2002)	
	C4	P.G. Carey, et al., "Polysilicon Thin-Film Transistors Fabricated on Low Temperature Plastic Substrates," J. Vac. Sci. Technol., A, 17(4) pp. 1946-49 (1999)	
	C5	U.S.S.N. 10/434,377, filed May 8, 2003, "Organic Polymers, Electronic Devices, and Methods" (Bai et al.)	
	C6	U.S.S.N. 10/620,027, filed July 15, 2003, "Bis[2-acenyl]Acetylene Semiconductors" (Gerlach)	
1/2	C7	U.S.S.N. 10/642919, filed August 18, 2003, "Method for Sealing Thin Film Transistors" (Muyres et al.)	

*Examiner:

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Date Considered:

10/11/05

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

Information Disclosure Statement)

Substitute for form 1448A/PTO (modified)

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	A1	US-			
	A2	US-			
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	A4	US-			
	A5	US-			
	A6	US-			
	A7	US-			
	A8	US-			
	A9	US-			
	A10	US-			
	A11	US-			

Foreign Patent Documents

Exam. Init.*	Cite No.	Foreign Patent Document		Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear	Translation (Check if yes)
		Ctry. Code	Number-Kind Code (if known)				
	B1						
	B2						
	B3						
	B4						
	B5						
	B6						
	B7						

OTHER DOCUMENTS

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80	C1	KIM et al., "Fabrication and Application of a Full Wafer Size Micro/Nanostencil for Multiple Length-Scale Patterning", Microelectronic Engineering, (2003), pp. 609-614, Vol. 67-68	
	C2		
	C3		

*Examiner:

Kw

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